

# Shigeyuki Morishita

## List of Publications by Year in descending order

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37  
papers

510  
citations

759233

12  
h-index

677142

22  
g-index

37  
all docs

37  
docs citations

37  
times ranked

735  
citing authors

#	ARTICLE	IF	CITATIONS
1	Position and momentum mapping of vibrations in graphene nanostructures. <i>Nature</i> , 2019, 573, 247-250.	27.8	96
2	Diffraction imaging of the dumbbell structure in silicon by spherical-aberration-corrected electron diffraction. <i>Applied Physics Letters</i> , 2008, 93, 183103.	3.3	54
3	Attainment of 40.5 pm spatial resolution using 300 kV scanning transmission electron microscope equipped with fifth-order aberration corrector. <i>Microscopy (Oxford, England)</i> , 2018, 67, 46-50.	1.5	51
4	Atomic resolution electron microscopy in a magnetic field free environment. <i>Nature Communications</i> , 2019, 10, 2308.	12.8	50
5	Unexpected Huge Dimerization Ratio in One-Dimensional Carbon Atomic Chains. <i>Nano Letters</i> , 2017, 17, 494-500.	9.1	35
6	Estimation of wave fields of incident beams in a transmission electron microscope by using a small selected-area aperture. <i>Journal of Electron Microscopy</i> , 2011, 60, 101-108.	0.9	33
7	Resolution enhancement in transmission electron microscopy with 60-kV monochromated electron source. <i>Applied Physics Letters</i> , 2016, 108, 013107.	3.3	29
8	High spatiotemporal-resolution imaging in the scanning transmission electron microscope. <i>Microscopy (Oxford, England)</i> , 2020, 69, 240-247.	1.5	27
9	Evaluation of residual aberration in fifth-order geometrical aberration correctors. <i>Microscopy (Oxford, England)</i> , 2018, 67, 156-163.	1.5	23
10	Atomic Resolution Imaging at an Ultralow Accelerating Voltage by a Monochromatic Transmission Electron Microscope. <i>Physical Review Letters</i> , 2016, 117, 153004.	7.8	22
11	Quantitative phase imaging of electron waves using selected-area diffraction. <i>Applied Physics Letters</i> , 2012, 101, 234105.	3.3	19
12	Imaging of isotope diffusion using atomic-scale vibrational spectroscopy. <i>Nature</i> , 2022, 603, 68-72.	27.8	14
13	Measurement of spatial coherence of electron beams by using a small selected-area aperture. <i>Ultramicroscopy</i> , 2013, 129, 10-17.	1.9	12
14	Development of tilt-scan system for differential phase contrast scanning transmission electron microscopy. <i>Microscopy (Oxford, England)</i> , 2022, 71, 111-116.	1.5	8
15	Resolution Achievement of 40.5 pm in Scanning Transmission Electron Microscopy using 300 kV Microscope with Delta Corrector. <i>Microscopy and Microanalysis</i> , 2018, 24, 120-121.	0.4	6
16	Phase imaging and atomic-resolution imaging by electron diffractive imaging. <i>Japanese Journal of Applied Physics</i> , 2019, 58, 120502.	1.5	6
17	Performance of Low-kV Aberration-corrected STEM with Delta-corrector and CFEG in Ultrahigh Vacuum Environment. <i>Microscopy and Microanalysis</i> , 2017, 23, 468-469.	0.4	4
18	Automated geometric aberration correction for large-angle illumination STEM. <i>Ultramicroscopy</i> , 2021, 222, 113215.	1.9	4

#	ARTICLE	IF	CITATIONS
19	New STEM/TEM Objective Lens for Atomic Resolution Lorentz Imaging. <i>Microscopy and Microanalysis</i> , 2017, 23, 456-457.	0.4	3
20	Development of a Monochromated and Aberration-Corrected Low-Voltage (S)TEM. <i>Microscopy and Microanalysis</i> , 2015, 21, 351-352.	0.4	2
21	Ultra High Energy Resolution EELS Mapping using Aberration-corrected Low-voltage STEM Equipped with Monochromator. <i>Microscopy and Microanalysis</i> , 2016, 22, 962-963.	0.4	2
22	Depth sensitive imaging of graphene with an atomic resolution microscope. <i>Applied Physics Letters</i> , 2018, 113, .	3.3	2
23	In-situ TEM observation of the growth process of carbon nanomaterials by laser irradiation. <i>Microscopy and Microanalysis</i> , 2021, 27, 2344-2345.	0.4	2
24	Aberration Measurement and Correction in Scanning Transmission Electron Microscopy using Machine Learning. <i>Microscopy and Microanalysis</i> , 2021, 27, 814-816.	0.4	2
25	Highly Depth-sensitive TEM Imaging of Graphene by using Monochromatic Electron Source at Low Accelerating Voltage. <i>Microscopy and Microanalysis</i> , 2018, 24, 1610-1611.	0.4	1
26	Development of Ultrahigh Resolution Objective Lens Enabling High Analytical Sensitivity. <i>Microscopy and Microanalysis</i> , 2020, 26, 3126-3128.	0.4	1
27	Atomic-Resolution Imaging of Graphene Using an Ultrahigh-vacuum Microscope with a High-brightness Electron Gun. <i>Microscopy and Microanalysis</i> , 2020, 26, 2358-2359.	0.4	1
28	Theoretical Study on Sixth-order Geometrical Aberration Correction. <i>Ultramicroscopy</i> , 2022, , 113569.	1.9	1
29	Analysis of Crystalline Nano Structures Embedded in Amorphous Films by Selected Area Nano Diffraction in a Cs-corrected TEM. <i>Microscopy and Microanalysis</i> , 2009, 15, 760-761.	0.4	0
30	Reconstruction of Atomic Columns in Silicon by Electron Diffractive Imaging. <i>Microscopy and Microanalysis</i> , 2009, 15, 744-745.	0.4	0
31	Determination of a 3D Lattice Displacement Field by Iterative Phase Retrieval of Rocking Curves of HOLZ Reflections. <i>Microscopy and Microanalysis</i> , 2011, 17, 1114-1115.	0.4	0
32	Phase Reconstruction Of Electron Waves Using Diffractive Imaging. <i>Microscopy and Microanalysis</i> , 2012, 18, 1250-1251.	0.4	0
33	Improvement of TEM Spatial Resolution at Low Accelerating Voltages (15-30 kV) with Monochromator. <i>Microscopy and Microanalysis</i> , 2016, 22, 982-983.	0.4	0
34	Nanoscale Vibrational Spectroscopy of Graphene by Large-q EELS. <i>Microscopy and Microanalysis</i> , 2019, 25, 612-613.	0.4	0
35	TV-rate Atomic-resolution STEM Imaging. <i>Microscopy and Microanalysis</i> , 2020, 26, 1150-1151.	0.4	0
36	Development of High-Speed Scan System for Atomic Resolution STEM. <i>Microscopy and Microanalysis</i> , 2021, 27, 2710-2712.	0.4	0

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37	Reprint of: Automated geometric aberration correction for large-angle illumination STEM. Ultramicroscopy, 2021, 231, 113410.	1.9	0